·	Application No.	Applicant(s)	
Nation of Allowability	10/665,934	LIU ET AL.	
Notice of Allowability	Examiner	Art Unit	
	Brook Kebede	2823	
The MAILING DATE of this communication appear All claims being allowable, PROSECUTION ON THE MERITS IS herewith (or previously mailed), a Notice of Allowance (PTOL-85) NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RI of the Office or upon petition by the applicant. See 37 CFR 1.313	(OR REMAINS) CLOSED in this app or other appropriate communication IGHTS. This application is subject to	olication. If not include will be mailed in due o	d course. THIS
1. This communication is responsive to 10 January 2005.			
2. The allowed claim(s) is/are <u>1,2,4-16,18 and 19</u> .			
3. \boxtimes The drawings filed on <u>19 September 2003</u> are accepted by	the Examiner.		
 4. Acknowledgment is made of a claim for foreign priority una a) All b) Some* c) None of the: 1. Certified copies of the priority documents have 2. Certified copies of the priority documents have 3. Copies of the certified copies of the priority documents have International Bureau (PCT Rule 17.2(a)). * Certified copies not received: 	been received. been received in Application No		on from the
Applicant has THREE MONTHS FROM THE "MAILING DATE" noted below. Failure to timely comply will result in ABANDONM	of this communication to file a reply (IENT of this application.	complying with the req	uirements
THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.			
5. A SUBSTITUTE OATH OR DECLARATION must be subm INFORMAL PATENT APPLICATION (PTO-152) which give	itted. Note the attached EXAMINER'es reason(s) why the oath or declara	'S AMENDMENT or Notion is deficient.	OTICE OF
6. CORRECTED DRAWINGS (as "replacement sheets") mus	st be submitted.		
(a) I including changes required by the Notice of Draftspers	on's Patent Drawing Review (PTO-	948) attached	
1) hereto or 2) to Paper No./Mail Date	• •		
 (b) ☐ including changes required by the attached Examiner's Paper No./Mail Date 	s Amendment / Comment or in the O	office action of	
Identifying indicia such as the application number (see 37 CFR 1, each sheet. Replacement sheet(s) should be labeled as such in the	.84(c)) should be written on the drawir he header according to 37 CFR 1.121(c	ngs in the front (not the	back) of
7. DEPOSIT OF and/or INFORMATION about the deposit attached Examiner's comment regarding REQUIREMENT	sit of BIOLOGICAL MATERIAL n FOR THE DEPOSIT OF BIOLOGICA	nust be submitted. N AL MATERIAL.	ote the
Attachment(s)	_		
1. Notice of References Cited (PTO-892)	5. Notice of Informal P	• • • • • • • • • • • • • • • • • • • •	-152)
2. Notice of Draftperson's Patent Drawing Review (PTO-948)	 Interview Summary Paper No./Mail Dat 	(PTO-413),	
3. Information Disclosure Statements (PTO-1449 or PTO/SB/0 Paper No./Mail Date 1/10/05	8), 7. ⊠ Examiner's Amendn		
4. Examiner's Comment Regarding Requirement for Deposit	8. 🛛 Examiner's Stateme	ent of Reasons for Allov	vance
of Biological Material	9. Other		
·			

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EXAMINER'S AMENDMENT

1. An examiner's amendment to the record appears below. Should the changes and/or

additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR

1.312. To ensure consideration of such an amendment, it MUST be submitted no later than the

payment of the issue fee.

Authorization for this examiner's amendment was given in a telephone interview with

Ms. Lie-Yea Cheng on February 16, 2005.

2. The application has been amended as follows:

In the Claims:

Please cancel Claim 3.

Change Claim 1 to:

-- A method for trimming photoresist features on a semiconductor substrate in a plasma

processing system, comprising: placing a substrate with a patterned photoresist layer having at

least one element with a first prescribed width on the substrate in the plasma processing system;

supplying to the process chamber a process gas mixture comprising a hydrocarbon gas, an

oxygen gas, and an inert gas, or a process gas mixture comprising a halogenated

hydrocarbon gas, an oxygen gas, and an inert gas, or a mixture the safe and disassociating

the process gas mixture to etch the patterned photoresist layer.---.

Change Claim 4 to:

-- The method of claim 1 wherein the halogenated hydrocarbon gas is CHF₃.--.

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Allowable Subject Matter

3. Claims 1, 2, 4-16, 18 and 19 are allowed over prior art of record.

Reasons for Allowance

4. The following is an examiner's statement of reasons for allowance:

The prior art of record neither anticipates nor renders obvious the claimed subject matter of the instant application as a whole either taken alone or in combination, in particular, prior art of record does not teach "supplying to the process chamber a process gas mixture comprising a hydrocarbon gas, an oxygen gas, and an inert gas, or a process gas mixture comprising a halogenated hydrocarbon gas, an oxygen gas, and an inert gas, or a mixture thereofs; and disassociating the process gas mixture to etch the patterned photoresist layer," as recited in claim 1.

Claims 2, 4-16, 18 and 19 are also allowed as being directly or indirectly dependent of the allowed independent claim.

Conclusion

5. Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Correspondence

6. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Brook Kebede whose telephone number is (571) 272-1862. The examiner can normally be reached on 8-5 Monday to Friday.

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If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Olik Chaudhuri can be reached on (571) 272-1855. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

BK

February 16, 2005

George Fourson
Primary Examiner